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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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PATENT COOPERATION TREATY

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Applicant:	Akinobu Sato, et al.
U.S. National Stage Application of International Application No.	PCT/JP2004/014275
International Filing Date:	September 29, 2004
Attorney Docket No.	NAA237
Title:	Solid surface smoothing method and apparatus therefor

March 29, 2006
San Francisco, California

Mail Stop PCT
Commissioner of Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Sir:

Pursuant to the duty of disclosure set forth in 37 CFR § 1.56, Applicants respectfully submit the following information disclosure statement.

The disclosed references are:

JP-2004-253437, Japanese Patent Office, published 09/09/2004, with its English abstract.

JP-2003-188156, Japanese Patent Office, published 07/04/2003, with its English abstract.

JP-2003-505867, Japanese Patent Office, published 2/12/2003, with its counterpart US application US 6,375,790 described below.

JP-2001-284252, Japanese Patent Office, published 10/12/01, with its English abstract.

10057394c

JP-02-000316, Japanese Patent Office, published 01/05/1990, with its English abstract.

JP2003170110 29 MAR 2006

PCT Application Publication No. WO-01/048794 dated 07/05/2001.

JP-07-058089, Japanese Patent Office, published 03/03/1995, with its English abstract.

JP-08-120470, Japanese Patent Office, published 05/14/1996, with its English abstract.

JP-08-293483, Japanese Patent Office, published 11/05/1996, with its English abstract.

Toyoda, et al., "Ultra-Smooth Surface Preparation Using Gas Cluster Ion Beams," Japanese Journal of Applied Physics, Vol. 41 (2002), pp. 4287-4290.


Yamada, et al., Materials Science and Engineering, R34 (2001), pp. 231-295.

Toyoda, et al., "Surface smoothing mechanism of gas cluster ion beams," Nuclear Instruments and Methods in Physics Research B 161-163 (2000) 980-985.

A thirteenth reference, US patent 6,375,790 B1, Fenner, issued 04-23-02, filed 10-5-99, is also being submitted because it is believed to be a counterpart to JP-2003-505867 and may serve as a translation thereof.

Applicants respectfully request that the Examiner initial the cited references shown on the enclosed form PTO-1449 and that the references be made of record in the present application.

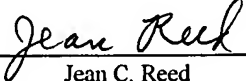
Respectfully submitted,


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Enc. PTO Form 1449
Cited references (13)
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Jean C. Reed

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